
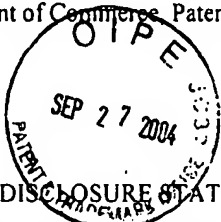


[illegible]

Examiner: 	Date Considered: 11/24/04
<p>* Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication with applicant.</p>	

U.S. Department of Commerce Patent and Trademark Office  INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	Application No.:	10/722,724
	Filing Date:	November 25, 2003
	First Named Inventor:	Peter G. Borden
	Group Art Unit:	2877
	Examiner Name:	Rosenberger
	Confirmation No.:	7346
	Attorney Docket No.:	BOX004-1C US

U.S. Patent Documents							
*Examiner Initials		Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
<i>R</i>	118.	6,211,961	4/3/03	Maris	356	432	
<i>R</i>	119.	6,268,916	7/31/01	Lee et al.	356	432	
<i>R</i>	120.	4,571,685	2/18/86	Komoshida	364	468	
Foreign Patent Documents							
							Translation
		Document	Date	Country	Class	Subclass	Yes No
<i>R</i>	121.	0 718 595	20.12.95	Europe	G01B	11/06	
<i>R</i>	122.	99/64880	16.12.99	WO	G01R	31/26	
Other Art (Including Author, Title, Date, Pertinent Pages, Etc.)							
<i>R</i>	123.	Paquin, "Properties of Metals", Handbook of Optics, Vol. II, McGraw-Hill, Inc. (month unavailable), 1995, pp. 35.3-35.7					
<i>R</i>	124.	Schroder, "Semiconductor Material and Device Characterization", John Wiley & Sons, Inc. (month unavailable), 1990, pp2-20, 84-85, 232-235, 304-306, 364, 367-374, 378-383.					
<i>m</i>	125.	J. Opsal, "High Resolution Thermal Wave Measurements and Imaging of Defects and Damage in Electronic Materials" Photoacoustic and Photothermal Phenomena II, Springer Series in Optical Sciences, Vol. 62, Springer Verlag Berlin, Heidelberg, 1990.					
<i>R</i>	126.	Rosencwaig, "Thermal Wave Characterization and Inspection of Semiconductor Materials and Devices", Chapter 5 (pp. 97-135) of Photoacoustic and Thermal Wave Phenomena in Semiconductors, North Holland (month unavailable) 1987					
<i>m</i>	127.	Constantinos Christofides "Photomodulated Thermoreflectance Investigation of Semiconducting Implanted Wafers," Microelectronic Engineering, 40 (1998), 251-261.					
<i>m</i>	128.	Bristow, Thomas C. and Dag Lindquist, "Surface Measurements With A Non-Contact Nomarski-Profilng Instrument", Interferometric Metrology, SPIE vol. 816, August 1987, pages 106-110					
<i>m</i>	129.	"Process Monitoring System", Quantox Product Brochure, 3 pages, published prior to March 1, 2002					
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<i>R</i>	131.	International Search Report PCT/US03/06239					
<i>R</i>	132.	International Search Report PCT/US01/07475					
<i>R</i>	133.	International Search Report PCT/US03/06379					
<i>R</i>	134.	International Search Report PCT/US03/02650					

Examiner: <i>[Signature]</i>	Date Considered: <i>24 Nov 2004</i>
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